

Operator-Oriented Operation for the Workplace Compact Surface Texture Measuring Instrument for Easy Operation





Roll foot





All-position pickup folder Horizontal trace pickup folder

LCD Panel Simplifies Operation

A Color LCD touch panel with a wide field of view is available.

Highly Portable Compact Unit

The unit is small enough for use at virtually any location.

Complied with International Standard Analysis Parameters

Desired standards such as JIS, ISO, DIN, ASME or CNOMO can be selected.

Satisfies European Directives for CE Marking

Able to Measure Level Difference and Film Thickness



(AI

Customize Icons

The customize function can be used to create a special menu where only the icons that are used most frequently are displayed, substantially enhancing operational efficiency.

AI Function (Patented)

The AI (artificial intelligence) function automatically selects the ideal cut-off value, measuring range and other conditions simply by entering the parameters and allowable values denoted on the machining drawing. This automates measurement.



Guidance Function

This function guides the user through the measuring procedures, enabling beginners to make measurements.



Memo Function

A short note or diagram can be entered with the touch pen and printed using the memo function.



Host of Analysis Functions

The unit incorporates 34 types of roughness parameters (Ra, Rz, Ry, Sm, S, tp, etc.) and 32 types of waviness parameters. Level difference of electrical parts, film thickness, surface area and other items can be analyzed with maximum precision.

Tilt Correction Function

Six types of automatic tilt correction are provided: Linear, first half, latter half, both end, round surface and spline curve (patented).

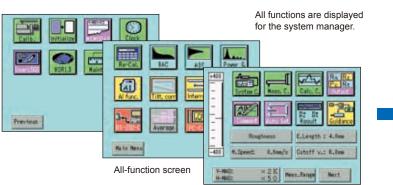


Evaluation Range Setting (Patented) The waveform on the screen is enclosed by two cursors, allowing the desired evaluation range to be set and the parameters to be calculated.

PC Card Slot

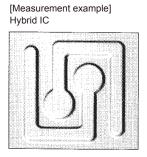
Measuring conditions and measured data can be stored in a PC card and read whenever necessary. This data can be output in text format and read on a personal computer. Storage of data on CF cards is also possible.

ACCRETECH TOKYO SEIMITSU

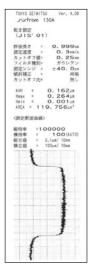


• Convenient Mode Select Function for System Manager/Operator

• Level difference profile evaluation function



Can be used for measurement of level difference, film thickness and area of hybrid IC, magnetic head, etc.



Only required functions are displayed for the operator.

AI +400 24 10 二 3 . 0.5aa/s 1 E.Length 1 4.7m ×2K ×50 -410 M.Speed: 0.500/s Cutoff v.: 0.3mm ×2K ×50 Mean.Range Customized screen

Data Sheet TOKYO SEIMITSU Jurfor 130A Ven. 5.08 パワーグラフR) 1822 Accreech Р-Р С1 6.400µ# 組さ測定 (JIS' O1) Č2 評価長さ 測定速度 カットオ . フ値・種別・ 0. 8 満定レンジ 単 傾斜相正 = カットオフ比。 300 Pe上限 Pe下限 波長 (原面曲線> 縦倍率 横倍率 縦目感 横目感 2000 tp 8.087,# 0.00% 0.22%

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Specifications

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Model		SURFCOM 130A
Measuring range	Z-axis (vertical)	800 μm (Measuring range/resolution: 800 μm/0.012 μm, 80 μm/0.001 μm, 8 μm/0.0001 μm)
	X-axis (horizontal)	50 mm
Straightness accuracy		0.3 μm/50 mm
Analysis items	Standards	Complies with JIS2001, JIS1994, JIS1982, ISO1997, ISO1984, DIN1990, ASME1995, CNOMO
	Parameters	Ra, Rq, Ry, Rp, Rv, Rc, Rz, Rmax, Rt, Rz.J, R3z, Sm, S, RΔa, RΔq, Rλa, Rλq, TILT A, Ir, Pc, Rsk, Rku, Rk, Rpk, Rvk, Mr1, Mr2, VO, K, tp, Rmr, tp2, Rmr2, Rσc, AVH, Hmax, Hmin, AREA, NCRX, R, Rx, AR, NR, CPM, SR, SAR
	Evaluation curves	Section profile curve, roughness curve, filtered waviness curve, filtered center line waviness curve, rolling circle waviness curve, rolling circle center line waviness curve, DIN4776 special curve, roughness motif curve, waviness motif curve, envelope waviness curve
	Surface characteristics graphs	Bearing area curve, amplitude distribution curve, power spectrum curve
	Tilt correction	Linear correction, round surface correction, first half correction, latter half correction, both end correction, spline curve correction (linear, round surface and both end correction possible in arbitrary range)
Magnifica- tion	Vertical (Z-axis)	50, 100, 200, 500, 1 k, 2 k, 5 k, 10 k, 20 k, 50 k, 100 k, auto
	Horizontal (X-axis)	1, 2, 5, 10, 20, 50, 100, 200, 500, 1 k, 2 k, 5 k, auto
Type of filter		Standard filter (2RC), phase compensation filter (2RC), phase compensation filter (Gaussian)
Measuring speed		0.3, 0.6, 1.5, 3 mm/s (4 speeds)
Detector		Tip radius: 2 µm, Material: Diamond, Measuring force: 0.75 mN
Special functions	AI function	Al function provide for easy procedures, enabling beginners to conduct measurements.
	Level difference analysis function	Ideal for film thickness and surface area measurement of semiconductor parts.
	PC card	Data output as text file for transfer to a personal computer.
Standard accessories		Reference specimen (E-MC-S24B), recording paper (E-CH-S21A), touch pen (E-MA-S54A), operation manual, support ware
Dimensions and weight	Power supply, frequency, consumption	AC 100 V to 240 V ±10%, 50 Hz/60 Hz, 30 VA
	Installation dimensions (W x D x H)	700 mm × 300 mm × 150 mm
	Weight	8 kg

*The correspondence to the special specification of measuring pressure power or stylus is also possible.

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